



**PATENT APPLICATION**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of

Docket No: Q60716

Hiromoto OHNO, et al.

Appln. No.: 10/088,306

Group Art Unit: 1754

Confirmation No.: 2926

Examiner: Paul A. Wartalowicz

Filed: March 18, 2002

For: CLEANING GAS FOR SEMICONDUCTOR PRODUCTION EQUIPMENT

**RESPONSE UNDER 37 C.F.R. § 1.111**

**MAIL STOP AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Responsive to the outstanding Office Action of November 16, 2005, once extended from February 16, 2006 to March 16, 2006 by the filing of an appropriate Petition and payment for extension of time submitted herewith, please consider Applicants' remarks as follows.

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